

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In Re Application of )  
 )  
Hiroki et al. )  
 )  
Serial No.: 09/776,472 )  
 )  
Filed: February 2, 2001 )  
 )  
For: Thin Film Formation Apparatus And )  
Method Of Manufacturing Self-Light- )  
Emitting Device Using Thin Film )  
Formation Apparatus )  
 )  
Art Unit: 1762 )  
 )  
Confirmation No.: 7144 )  
 )  
Examiner: James Lin )

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT (K)**

Sir:

Applicants have the following response to the Office Action of December 11, 2006.

Please amend the above-identified application as follows: